IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Hideshi NISHIKAWA et al.

Serial No.:

not yet assigned

Filed:

March 26, 2004

For:

SILICON ANNEALED WAFER AND SILICON EPITAXIAL WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

Applicants respectfully submit that this disclosure is being made with the filing of the application, hence, no fee is required.

Respectfully submitted,

CLARK & BRODY

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Docket No.: 12054-0025 Date: March 26, 2004

													
FORM PTO-1449 INFORMATION DISCLOSURE CITATION		Attorney	Attorney Docket: 12010-0025				Serial No.: not yet assigned						
GITATION													
		Applica	Applicant: Hideshi NISHIKAWA et al.										
	Filing D	Filing Date: March 26, 2004			Group: not yet assigned								
		U.S. P	ATENT	DOCUMENTS									
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Examiner Initial	Document Number	Date		Country		Class		Sub- Class		Translation Yes No			
	10-098047	04/14/1998		Japan						X			
	11-189493	07/13/1999		Japan						X			
	2001-199795	07/24/2001		Japan						х			
	2002-187794	07/05/2002		Japan						X			
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	OTHER DOCUME	NTS (Includ	ling Aut	hor, Title, Date, Pertine	ent Pa	ges, e	etc.)						
	K. Nakai; "NITROGEN AND CARBON EFFECT ON THE FORMULATION OF GROWN-IN DEFECTS AND OXYGEN PRECIPITATION BEHAVIOR"; The 52 nd Conference of the Japanese Association for Crystal Growth, Bulk Growth Section Meeting; February 8, 2000, pages 6-9												

Examiner:	Date Considered:				
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.					